A semiconductor substrate (78) processing apparatus and a method for processing semiconductor substrates (78) are provided. The semiconductor substrate (78) processing apparatus may include a liquid container (62) where a semiconductor substrate (78) may be immersed in a semiconductor processing liquid (64). The semiconductor substrate may then be removed from the semiconductor processing liquid while vapor (76) is directed at a surface of the semiconductor substrate (78) where the semiconductor substrate contacts a surface of the processing liquid (64).

Published:
— with international search report
— before the expiration of the time limit for amending the claims and to be republished in the event of receipt of amendments

publication of the international search report:
23 October 2008
INTERNATIONAL SEARCH REPORT

A. CLASSIFICATION OF SUBJECT MATTER
IPC: B08B 3/02 (2006.01)

USPC: 134/102.1
According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED
Minimum documentation searched (classification system followed by classification symbols)
U.S.: 134/102.1, 94.1, 95.2, 99.1, 83, 198, 902

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practicable, search terms used)

C. DOCUMENTS CONSIDERED TO BE RELEVANT

<table>
<thead>
<tr>
<th>Category</th>
<th>Citation of document, with indication, where appropriate, of the relevant passages</th>
<th>Relevant to claim No.</th>
</tr>
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<tbody>
<tr>
<td>A</td>
<td>US 5,571,367 A (NAKAJOIMA et al.) 05 NOVEMBER 1996 (05.1 1.1996).</td>
<td>1-25</td>
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<tr>
<td>X</td>
<td>US 6,192,600 a (BERGMAN) 27 FEBRUARY 2001 (27.02.2001), see cols. 1-10.</td>
<td>1-25</td>
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<tr>
<td>X</td>
<td>US 6,2 19,936 A (KEDO et al.) 24 APRIL 2001 (24.04. 2001), see cols 1-12.</td>
<td>1-25</td>
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<tr>
<td>A</td>
<td>US 6,532,974 A (KASHKOUISH et al.) 18 MARCH 2003 (18.03.2003)</td>
<td>1-25</td>
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</tbody>
</table>

Further documents are listed in the continuation of Box C
See patent family annex.

Date of the actual completion of the international search: 04 August 2008 (04.08.2008)
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